

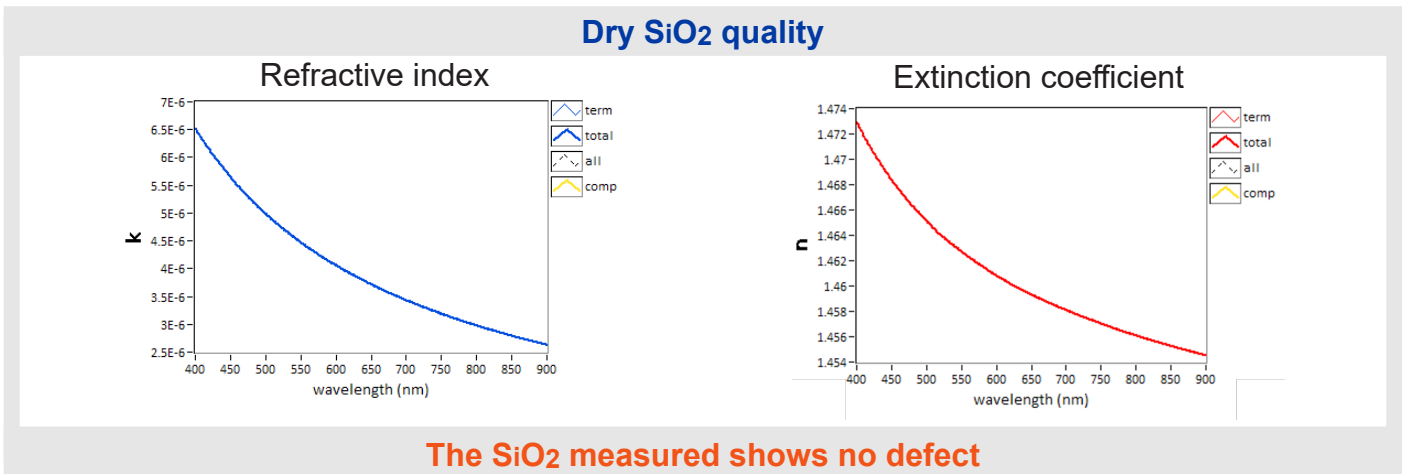
# Thin film Layers



- Totally customized
- Dry oxidation
- Breakdown voltage:  
>200 V for 285 nm thick layer
- Low Roughness  
( $< 3 \text{ \AA RMS}$ )
- Any metallic layers
- Multilayers deposition



| Oxidation & Deposition on Silicon | Thickness (nm) | Thickness tolerances (µm) | Diameters     |
|-----------------------------------|----------------|---------------------------|---------------|
| <b>Oxidation</b>                  |                |                           |               |
| Wet oxidation                     | 200 - 3000     | ± 3%                      | From 1" to 6" |
| High purity dry oxidation         | 20 - 300       | ± 5%                      | From 1" to 6" |
| <b>Option</b>                     |                |                           |               |
| Single face oxidation             |                |                           |               |



| Single layer deposition / metallization                                    |                   |          |                    |                                      |
|--|-------------------|----------|--------------------|--------------------------------------|
| Silicon nitride  | LPCVD             | 20 - 500 | Option: Low Stress | From 2" to 6"                        |
|  | PECVD             |          |                    |                                      |
| Oxide nitride  | PECVD             | 20 - 500 | From 1" to 6"      | From 2" to 4"                        |
| Polysilicon  | LPCVD             | 20 - 600 | From 1" to 4"      |                                      |
| Cr, Ti, Au, Al, Pt, Mo, W<br>Highly reflective silver coating              | PVD<br>sputtering |          |                    |                                      |
| Ni, Cu, Ir, Ta, Al <sub>2</sub> O <sub>3</sub>                             | Evaporation       | 20 -1000 | ± 10%              | From 1" to 6"<br>depending on metals |
| Cr/Au<br>TiW with Ti : 10% W: 90%<br>TiW /Au with Ti : 10% W: 90%<br>Ti/Pt | PVD               |          |                    |                                      |

| Multilayers deposition |
|------------------------|
| On request             |

